

PATENT ASSIGNMENT

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SUBMISSION TYPE:	NEW ASSIGNMENT
NATURE OF CONVEYANCE:	ASSIGNMENT
CONVEYING PARTY DATA	
Name	Execution Date
OC Oerlikon Balzers AG	10/27/2011
RECEIVING PARTY DATA	
Name:	Oerlikon Solar AG, Truebbach
Street Address:	Hauptstrasse 1a
City:	Truebbach
State/Country:	SWITZERLAND
Postal Code:	9477
PROPERTY NUMBERS Total: 15	
Property Type	Number
Application Number:	11877419
Patent Number:	5422139
Patent Number:	5693238
Patent Number:	5515986
Patent Number:	5852275
Patent Number:	6074691
Patent Number:	6296735
Patent Number:	6281469
Patent Number:	6533534
Patent Number:	6177129
Patent Number:	6391377
Patent Number:	6502530
Patent Number:	6890862
Patent Number:	6673255
Patent Number:	7306829

OP \$600.00 11877419

CORRESPONDENCE DATA

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NAME OF SUBMITTER:

Joerg Baur

Total Attachments: 4

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ASSIGNMENT

THIS ASSIGNMENT is made this 27 day of October, 2011.

Between:

OC Oerlikon Balzers AG, a corporation, and having a place of business at Iramali 18, 9496 Balzers, Liechtenstein (hereinafter called the Assignor)

and

Oerlikon Solar AG, Trübbach, a corporation, and having a place of business at Hauptstrasse 1a, CH-9477 Trübbach, Switzerland (hereinafter called the Assignee)

WHEREAS, the Assignor is the owner of patents and patent applications, short particulars of which are set out in Schedule A attached hereto.

WHEREAS, Assignee is desirous of acquiring all the rights in and to the patents.

WHEREAS, good and valuable consideration has been exchanged between the Assignor and the Assignee and the consideration was sufficient.

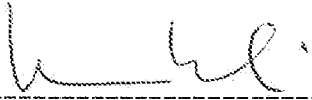
NOW, THEREFORE, be it known that, for the valuable consideration, the receipt and sufficiency of which are hereby acknowledged, the Assignor does hereby:

1- Assign to the Assignee, its successor and assigns, all property, right, title and interest to the patents and including the right to sue for damages and other remedies in respect of any infringement which may have occurred prior to the date hereof.


2 - Covenant to execute all documents, forms and authorizations and depose to or swear any declaration or oath as may reasonably be required for absolutely vesting full right, title and interest in the patents in favor of the Assignee.

IN WITNESS WHEREOF this Assignment has been executed by or on behalf of the parties hereto on the date first written above.

Signed for and on behalf of OC Oerlikon Balzers AG



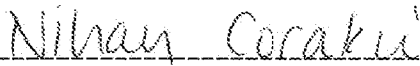
Name: Erich Haefeli
Title: General Counsel



Name: Jörg Baur
Title: Head of Patent Department



Witness



Witness

SCHEDULE A

OC Oerlikon Balzers AG to Oerlikon Solar AG, Trübbach

Patent Application

<u>SERIAL NO.</u>	<u>TITLE</u>
11/877,419	RF PLASMA REACTOR HAVING A DISTRIBUTION CHAMBER WITH AT LEAST ONE GRID

Patents

<u>Patent Number</u>	<u>Title</u>
5,422,139	METHOD FOR A REACTIVE SURFACE TREATMENT OF A WORKPIECE AND A TREATMENT CHAMBER FOR PRACTICING SUCH METHOD
5,693,238	METHOD FOR IMPROVING THE RATE OF A PLASMA ENHANCED VACUUM TREATMENT
5,515,986	PLASMA TREATMENT APPARATUS AND METHOD FOR OPERATING SAME
5,852,275	HEATING SYSTEM, VACUUM PROCESS CHAMBER COMPRISING SUCH A HEATING SYSTEM AND OPERATION OF SUCH A VACUUM PROCESS CHAMBER
6,074,691	METHOD FOR MONITORING THE FLOW OF A GAS INTO A VACUUM REACTOR
6,296,735	PLASMA TREATMENT APPARATUS AND METHOD FOR OPERATION SAME
6,281,469	CAPACITIVELY COUPLED RF-PLASMA REACTOR
6,533,534	METHOD FOR IMPROVING THE RATE OF A PLASMA ENHANCED VACUUM TREATMENT
6,177,129	PROCESS FOR HANDLING WORKPIECES AND APPARATUS THEREFOR
6,391,377	PROCESS FOR VACUUM TREATING WORKPIECES, AND CORRESPONDING PROCESS EQUIPMENT

6,502,530	DESING OF GAS INJECTION FOR THE ELECTRODE IN A CAPACITIVELY COUPLED RF PLASMA REACTOR
6,890,862	PROCESS FOR VACUUM TREATING WORKPIECES, AND CORRESPONDING PROCESS EQUIPMENT
6,673,255	PLASMA TREATMENT APPARATUS AND METHOD FOR OPERATING SAME
7,306,829	RF PLASMA REACTOR HAVING A DISTRIBUTION CHAMBER WITH AT LEAST ONE GRID